Scaling of electron temperature and soft x-ray intensity in laser-produced heavy element highly charged ions

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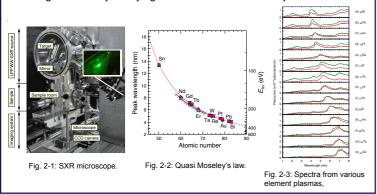
1. Abstract

EUV and soft x-ray (SXR) sources are very important to study radiation hydrodynamics, opacities, photo-ionized plasmas, and plasma diagnostics. There is particular interest in the relationship between electron temperature and emission spectra, which result from the balance between the emissivity and opacity in the spectral region of interest. On the other hand, it is important to understand the energy flow, related to the radiation transport, by highly charged ions (HCIs) in heavy element (high-*Z*) plasmas. We successfully achieved an optically thin state in laser-produced heavy element plasmas at determined electron temperatures, which have been predicted by the power balance and the collisional-radiative (CR) models. We also mapped the power-loss processes in sub-ns and ns laser-produced high-*Z* plasmas. The electron temperature evaluation was in good agreement with the power balance model and was supported by the spectral analysis. The output flux in the soft x-ray region was stronger at higher critical density.

2. Background

EUV and SXR sources are deeply related to heavy elements highly charged ions. These sources are expected for EUV lithography, condensed matter physics, SXR microscope etc. . In applications, it is necessary to reduce the size of light source due to the optical systems behind light source. Therefore, we use laser produced plasma (LPP) that the size of light source is sub-millimeter order.

We need to consider the conditions such as electron temperature and laser intensity for generating a light source suitable for each objectives. It is expected that it becomes possible to contribute to the application field of the light source by clarifying these conditions for heavy elements.



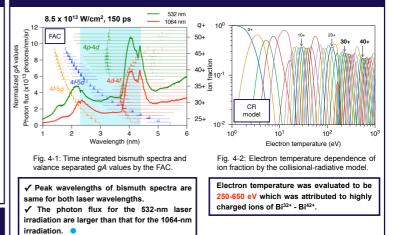
3. Objective

We focused on the bismuth plasma used in our microscope for *in vivo* biological imaging in water-window SXR spectral region. *Our objective is to observe the SXR spectra and to evaluate the electron temperature of a laser-produced bismuth plasma.*

The calibrated spectrometer was a flat-field grazing incidence type with an unequally ruled 2400 grooves/mm variable line space grating with a spectral resolution of 0.01 nm. The spectrometer was positioned at 30° with respect to the incident laser axis.

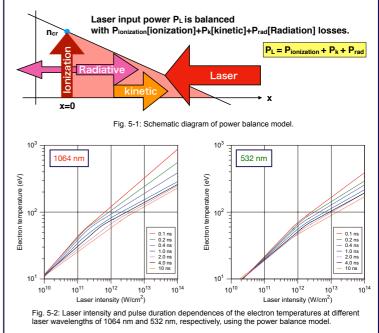
We evaluate the contributed ionic charge states of the UTA spectral peaks by the FAC and the electron temperature dependence of the ion fraction by the collisional-radiative (CR) model at different critical densities for two laser wavelengths of 1064 and 532 nm, respectively.

4. Results and discussion



5. Power balance model

✓ UTA peaks were attributed to highly charged ions ranging from Bi³²⁺to Bi⁴²⁺. - -



6. Summary

We have investigated the spectral behaviors at different laser wavelengths at 1064 nm and 532 nm in sub-nanosecond pulse duration. We also have evaluated the electron temperatures by the CR model.

- The UTA peaks was around 3.9 nm at different laser wavelengths.
- ▶ The photon flux for 532-nm irradiation was larger than that for 1064-nm.
- The output photon flux was 1×10^{14} photons/nm/sr for 532-nm.
- ▶ The UTA peaks were attributed to Bi³²⁺ Bi⁴²⁺.
- ▶ The optimum electron temperature was broadly 250-650 eV.